

RADIO FREQUENCY GROUNDING APPARATUS

ABSTRACT OF THE DISCLOSURE

The RF (Radio Frequency) grounding apparatus of the present invention uses a clamp to clamp an RF grounding rod by surface contact to improve the connection stability. The clamp is connected to a flexible
5 conductive sheet to form a grounding path to avoid the arcing generated by the bottom part (e.g., a heater) of a traditional plasma reaction chamber and to avoid breakage of the ceramic surface of the bottom part of the plasma reaction chamber, which would be caused by the RF grounding rod due to thermal expansion. Therefore, the heater of the plasma reaction chamber,
10 which is equipped with the RF grounding apparatus of the present invention, exhibits an extended lifetime. The top of the RF grounding rod is fixed to an RF mesh, and the RF grounding rod extends downward. The bottom of the RF grounding rod is clamped firmly and electrically by the clamp. The flexible conductive sheet connects the clamp and the grounding base of the
15 plasma reaction chamber to form a grounding path.

(FIG. 3)